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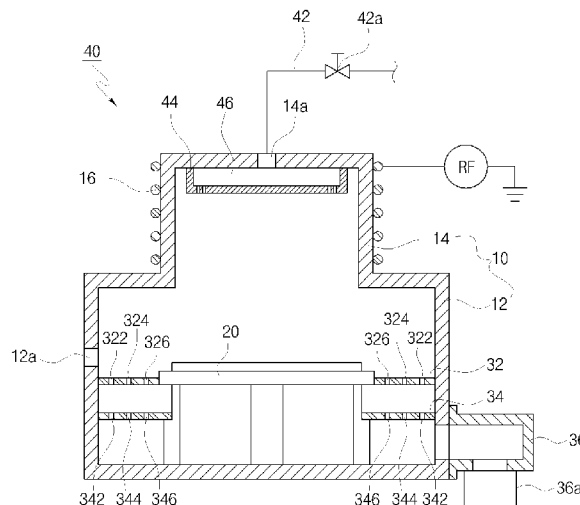
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(54) Title: SUBSTRATE PROCESSING APPARATUS

[Fig. 1]



(57) Abstract: A substrate processing apparatus includes a chamber defining an inner space where a process is carried out with respect to a substrate, a support member disposed in the chamber for supporting the substrate, and a guide tube disposed above the support member for guiding plasma generated in the inner space to the substrate on the support member. The guide tube is configured in the shape of a cylinder having a sectional shape substantially corresponding to the shape of the substrate, and the guide tube discharges the plasma introduced through one end thereof to the support member through the other end thereof. The chamber includes a process chamber in which the support member is disposed and a generation chamber disposed above the process chamber. The process is carried out by the plasma in the process chamber, and the plasma is generated by a coil in the generation chamber.

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Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Korean utility models and applications for Utility models since 1975.

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eKIPASS(kipo internal) & Keywords :Deposition, guide tube, processing, substrate.

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y A	KR 10-2006-0018261 A (TOKYO ELECTRON LIMITED) 28 February 2006 See page 4 lines 19- line26 and figure 1.	1 1-5
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 Further documents are listed in the continuation of Box C. See patent family annex.

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